

MASS FLOW RATE CONTROLLER

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Abstract of JP3111914

PURPOSE:To expand a flow rate range scarcely changing the fixing method of an existing mass flow rate controller by connecting a gas flow rate measuring sensor tube between primary and secondary rooms. **CONSTITUTION:**A body 1 is constituted of an inlet flange 14 and an outlet flange 15 respectively fixed to both the ends of a body 16. A cylindrical hole 17 opened to one end is formed on the body 16 and a primary/secondary side L-shaped hole 19 connected to the valve room 18 of a control valve part is formed on the bottom center of the hole 17. Diaphragms 5 for dividing the hole 17 are air-tightly inserted into the center of the cylinder 17 to separate the primary room from the secondary room. A sensor part is constituted of a sensor tube 9 and a differential pressure increasing spacer 12 and two differential pressure increasing conduits 10 are formed in the spacer 12.

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